

Trends on Montel X-ray Optics and Pinholes for Synchrotron Beamlines





Jörg Wiesmann – Founder & Managing Director Incoatec GmbH, Geesthacht, Germany



Incoatec: Innovative Coating Technologies





- Founded 2002 by scientists of GKSS Research Center together with Bruker AXS
- Located in the Geesthachter Innovation&Technology Center (near Hamburg)
- 4.100 m² building for Production and Development of X-ray Optics and Tubes
- Use deposition facilities for optimized Optics with different sizes, film gradients and precisions
- Offer equipment for home-lab instruments and synchrotron beamlines



X-ray Optics Design

Key know-how: Multilayer X-ray optics Substrates





For 1- or 2-dimensional beam focusing or collimating





Key know-how: Multilayer X-ray optics Coatings





 $m \cdot \lambda = 2 \cdot d \cdot \sin \Theta$ d = 1 - 8 nm $\theta_{\text{m}} \approx 1.0^{\circ} (\text{Cu-K}_{\alpha}, 8 \text{ keV})$

$\theta_{\rm m} \approx 0.5^{\circ} \; ({\rm Mo-K}_{lpha}, \; {\rm 17.5 \; keV})$

Multilayers act as Bragg reflector

- 100-400 layer pairs
- Interface roughness < 10%</p>
- Tolerance in *d* spacing better +/- 0.2 %



X-ray Optics Production

Key know-how: Multilayer X-ray optics Magnetron Sputtering

- Monolayer
- Homogenous Multilayer
- Lateral Graded-Multilayer
- Depth Graded Multilayer
- Stripe-Multilayer

Substrates: Silicon, Quartz, Zerodur ...

Film thickness: single layer 0.5 ... 500 nm

Target materials: wide variety!

Total reflection: C, SiC, Rh, Ru, Au, W, Cr,...

ML-Reflector: W, WSi₂, Ru, V, La, Mo, TiO₂, Ni ...

ML-Spacer: C, BN, B_4C , Si,...





Characterization of Multilayer: Diffractometer for XRR





Characterization of Multilayer: Diffractometer for XRR





Standard d-spacing accuracy within +- 1% on 150 mm, best: < 0.2 % on 500 mm



Examples at Synchrotrons

X-ray optics: Multilayer coating on bendable mirror



400 mm Si mirror with graded multilayer coating (Ru / C, 200 pairs for 7 – 20 keV)





d-spacing accuracy better 0.2% over 500 mm!

Helmholtz-Zentrum Geesthacht Zentrum für Material- und Küstenforschung Dr. Michael Störmer



Double crystal multilayer monochromator with 2 stripes or more!



TOMCAT tomography beamline, M. Stampanoni

Swiss Light Source



Stripe A :	[Ru/C]100,	, d = 4 nm
	R > 80%	for 10 < E < 22 keV

Midspace: Si111 $\Delta_{\text{orientation}} < 0.01^{\circ}$ $\sigma = 0.1 \text{ nm}$ slope error 0.04"

Stripe B : [W/Si]100, d = 3 nm R > 80% for 22 < E < 45 keV



- can be combined with synchrotron, X-ray laser, plasma or metal jet sources
- Optics for typical energies available
 (5..25 keV; Cu, Mo, Ag, Ga, In, Cr, Co, Fe, ...)
 lower E on request)
- Collimating and focusing or hybrid (line focus), length 60 ... 250 mm



Applications: Montel Optics for inelastic x-ray scattering





Some publications with our Montel Optics



research papers

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Tests and characterization of a laterally graded multilayer Montel mirror

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Multilayers are becoming an increasingly important tool in X-ray optics. The essential parameters to design a pair of laterally graded multilayer mirrors arranged in a Montel-type configuration for use as an X-ray collimating device are provided. The results of X-ray reflectometry tests carried out on the optics in addition to metrology characterization are also shown. Finally, using experimental data and combined with X-ray tracing simulations it is demonstrated that the mirror meets all stringent specifications as required for a novel ultra-high-resolution inelastic X-ray scattering spectrometer at the Advanced Photon Source.

Keywords: X-ray optics; collimating optics; Montel mirrors; laterally graded multilayers; KB mirrors.

KB NIXS

2014

research papers

Performance of a collimating L-shaped laterally graded multilayer mirror for the IXS analyzer system at NSLS-II

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The L-shaped laterally graded multilayer mirror is a vital part of the ultrahighenergy and momentum-resolution inelastic X-ray scattering spectrometer at the National Synchrotron Light Source II. This mirror was designed and implemented as a two-dimensional collimating optic for the analyzer system. Its performance was characterized using a secondary large-divergence source at the 30-ID beamline of the Advanced Photon Source, which yielded an integrated reflectivity of 47% and a collimated beam divergence of 78 µrad with a source size of 10 µm. Numerical simulations of the mirror performance in tandem with the analyzer crystal optics provided details on the acceptance sample volume in bility gular

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To be clarified in a project from the beginning with high impact on prizes:

- Substrates -> length, quality, characterization, responsibility
- Energy range -> multilayer material / multistripes (collaboration between user and us)
- Resolution -> precision of deposition, substrate quality
- Characterization -> test samples, test methods, when, what, where and how



Optics plus Microfocus Sources

Tube + Optics -> Brilliant Microfocus Source





Anode spot \sim 35 µm, energies up to 60 keV; Radiation: Cu, Mo, Ag, Cr, Co, (XRD), Rh, W (XRF), Ti (special), ...





Perfect Match: Multilayer Mirrors and Microfocus X-ray Beams

View angle = Bragg peak width



1 mrad = 0.057 deg



Impressions: Special Installations with $\ensuremath{\mbox{I}\mu\mbox{S}}$

Iµs @ Synchrotrons:

for characterizing equipment or measurements during downtime periods





Calibration of Detectors with Small X-ray Tube



Applications of the iXmini : Accurate flat field detector calibration

- Non-radioactive calibrant
- No need for fluorescence metal foil and external X-ray source
- Operation in vacuum possible

22

- Small footprint (120 x 105 x 90 mm³)
- Typical operation at 10 kV and 10 μA



Tube: 3 cm in length, Ø 1.2 cm





Intensity Distribution of a 1000 s Image without and with Flat Field Correction





Scatterless Pinholes

Scatterless pinholes for reduction of parasitic scattering (SCATEX)





- Smaller beam stop, thus higher resolution
- Larger beam defining pin-hole, thus more flux
- No antiscatter pin-hole, thus smaller setup



SCATEX at synchrotron: Parasitic aperture scattering at 8 keV





- Measurement time with SCATEX was 10x longer !
- SCATEX shows much less scattering into the q-space.
- Scattering pattern of SCATEX is circular -> high overall quality of the pinhole
- Material: Single Crystals of Ge for < 12 keV, Ta for > 12 keV; sizes: 20 ... 2000 μm



Summary

Your Partner for X-Ray Optics, X-ray Tubes, Microfocus Sources and Synchrotron Solutions











- X-ray Optics
- X-ray Tubes
- Microfocus Sources
- Scatterless Pinholes
- Solutions for Synchrotrons











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We are ready for new solutions!

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THANK YOU !







Bonus Material

Range of Solutions







- Beam shaping in 1 or 2 dim
- Focusing & collimating
- Optics for XRD (5-25 keV)
- XRF analyzers for low energies (0.2-1.5 keV)





Synchrotron Optics

- Thin film deposition
- (graded) Multilayer
- Multi stripe coatings
- Total reflection coatings
- Coatings up to 150 cm

Scatterless Pinholes

• Material:

Ge for < 12 keV

- Ta for > 12 keV
- Sizes (pinhole diameter): for Ge: 100 ... 2000 μm for Ta: 20 ... 1000 μm

Range of Solutions





Microfocus X-ray Tubes

- for Cu, Mo, Ag, Cr, Rh, W, Ti radiation (Others on request)
- Anodes with diamond cooling available



Microfocus Source Iµs

with inhouse-developed X-ray Tube

- High brilliant low power sealed tube
- New 2D optics
- For Crystallography, XRD, SAXS, ...

Publications with our synchrotron optics

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Keywords: X-ray optics; X-ray multilayer mirrors; laterally graded multilayer mirrors.



2018

E= 11215 eV

ESRF: Montel Multilayer Collimator Optics for ID20



ID20 beamline is dedicated to the study of electronic excitations in complex materials by means of resonant (RIXS) and non-resonant (NIXS) inelastic X-ray scattering. The MMCO will be part of a novel RIXS spectrometer, which will feature simultaneous energy and polarisation analysis of the beam scattered by the sample. This so-called polarimeter will be optimised at a working energy of 11215 \pm 20 eV.

IXT – Incoatecs Microfocus Tube



Simulation of Heat Transfer and Electron Beam Properties for Microfocus Tube





Homogeneity of a 40 s exposure using a modern CPAD detector (High Gain Mode)

- iXmini
 - Operated at 10 kV and 10 µA
 - Set at ~350 mm from the detector
- CPAD Detector (PHOTON III from Bruker)
 - Calibrated for Flat Field and Dark Current



A selection of our synchrotron customers



